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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
10/616,251	07/08/2003	Peter Martin	484	9476
7590 109022008 JOHN R. ROSS TREX ENTERPRISES 10455 PACIFIC CENTER CT. SAN DIEGO, CA 92121			EXAMINER	
			YANG, NELSON C	
			ART UNIT	PAPER NUMBER
			1641	
			MAIL DATE	DELIVERY MODE
			10/02/2008	PAPER

Please find below and/or attached an Office communication concerning this application or proceeding.

The time period for reply, if any, is set in the attached communication.

Notice of Allowability

Application No.	Applicant(s)			
10/616,251	MARTIN ET AL.			
Examiner	Art Unit			
Nolson Vana	16/1			

-- The MAILING DATE of this communication appears on the cover sheet with the correspondence addresstive

All claims being allowable, PROSECUTION ON THE MERITS IS (OR R herewith (or previously mailed), a Notice of Allowance (PTOL-85) or oth NOTICE OF ALLOWABILITY IS NOT A GRANT OF PATENT RIGHTS of the Office or upon petition by the applicant. See 37 CFR 1.313 and N	er appropriate communication will be mailed in due course. THIS This application is subject to withdrawal from issue at the initial
1. This communication is responsive to the response filed April 21,	2008.
2. The allowed claim(s) is/are 1-27,29-34, 36-47, renumbered 1-45.	
	received.
International Bureau (PCT Rule 17.2(a)). * Certified copies not received:	
Applicant has THREE MONTHS FROM THE "MAILING DATE" of this noted below. Failure to timely comply will result in ABANDONMENT o THIS THREE-MONTH PERIOD IS NOT EXTENDABLE.	
 A SUBSTITUTE OATH OR DECLARATION must be submitted. N INFORMAL PATENT APPLICATION (PTO-152) which gives reas 	
5. CORRECTED DRAWINGS (as "replacement sheets") must be su	ubmitted.
(a) ☐ including changes required by the Notice of Draftsperson's P	atent Drawing Review (PTO-948) attached
 hereto or 2) to Paper No./Mail Date 	
(b) ☐ including changes required by the attached Examiner's Amer Paper No./Mail Date	ndment / Comment or in the Office action of
Identifying indicia such as the application number (see 37 CFR 1.84(c)) each sheet. Replacement sheet(s) should be labeled as such in the head	
 DEPOSIT OF and/or INFORMATION about the deposit of B attached Examiner's comment regarding REQUIREMENT FOR T 	
Attachment(s)	_
Notice of References Cited (PTO-892)	Notice of Informal Patent Application
2. Notice of Draftperson's Patent Drawing Review (PTO-948)	 Interview Summary (PTO-413), Paper No./Mail Date
Information Disclosure Statements (PTO/SB/08), Paper No./Mail Date	7. X Examiner's Amendment/Comment
4. Examiner's Comment Regarding Requirement for Deposit	8. X Examiner's Statement of Reasons for Allowance

- of Biological Material
- 9. Other _____.

/Nelson Yang/ Patent Examiner, Art Unit 1641

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DETAILED ACTION

EXAMINER'S AMENDMENT

An examiner's amendment to the record appears below. Should the changes and/or additions be unacceptable to applicant, an amendment may be filed as provided by 37 CFR 1.312. To ensure consideration of such an amendment, it MUST be submitted no later than the payment of the issue fee.

Authorization for this examiner's amendment was given in a telephone interview with John Ross on August 11 and September 15, 2008. This examiner's amendment includes amendments to the claims made in the Examiner's amendment mailed August 26, 2008.

Please amend the Brief Description of the Drawings in the specification as follows: On p. 4, line 21, please change FIGS. 6A&B to FIGS. 6A-C.

On p. 4, line 24, please change FIG. 9 to FIG. 9A-F.

On p. 5, line 6, please change FIG. 15 to FIGS. 15A and 15B

In claims 32, 36, 37 please change "The method as in claim 27" to "The method as in claim 31". In claims 33 and 34, please change "The method as in claim 28" to "The method as in claim 32". Please cancel claim 35.

In claims 39 and 40, please change "The sensor as in claim 34" to "The sensor as in claim 38". In claims 45-47, please change "Claim" to "claim".

Please amend claims 1, 31, 38, 41, 42, and 45 as follows:

An optical sensor for monitoring molecular binding interactions, said sensor comprising:
 A) at least one porous silicon region comprising more than 1000 pores, each pore having a nominal width and a nominal depth at least 10 times larger than said nominal width, with the

depth of each pore being approximately equal to the depth of at least most other pores in said porous silicon region, said porous silicon region defining a top surface and a bottom surface, and said bottom surface being parallel or approximately parallel to said top surface;

- B) at least one buffer-sample fluid flow channel located above said at least one porous silicon region providing a fluid flow passage across said porous silicon region;
- C) at least one light source for illuminating said at least one porous silicon region;
- D) at least one interference monitor adapted to monitor interference patterns caused by interference of light reflected from said top surface with light reflected from said bottom surface of said at least one porous silicon region, said interference monitor comprising a deep well linear photodiode array of pixels, each pixel having a photoelectron full well capacity of about 156 million photoelectrons or more, and having a frame rate of about one hundred or more frames of interference fringe data per second;
- E) a fluid flow control system for producing controlled flow of buffer solutions, ligand containing solutions, and analyte containing solutions through said at least one fluid flow channel; and
- F) a computer processor programmed with a computer program for making causing said processor to execute molecular binding measurements based on changes in the interference patterns monitored by the at least one interference monitor while analytes bind with and disassociate from ligands attached to surfaces of said pores, said computer program comprising a special correlation method executable instructions for calculating optical path differences in measured interference fringe patterns wherein the measured fringe patterns is that are correlated

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to a test fringe pattern, wherein the test fringe pattern varies sinusoidally as a function of optical

path differences divided by the wavelength of said light.

31. A method for measuring molecular binding interactions, utilizing an optical sensor

comprising having:

a) at least one porous silicon region comprising more than 1000 pores, each pore having a

nominal width and a nominal depth at least 10 times larger than said nominal width, with the

depth of each pore being approximately equal to the depth of at least most other pores in said

porous silicon region, said porous silicon region defining a top surface and a bottom surface, $\underline{\text{and}}$

said bottom surface being parallel or approximately parallel to said top surface;

b) at least one buffer-sample fluid flow channel located above said at least one porous silicon

region providing a fluid flow passage across said porous silicon region;

c) at least one light source for illuminating said at least one porous silicon region;

d) at least one spectral interference monitor for adapted to monitoring interference fringe patterns

caused by interference of light reflected from said top surface with light reflected from and said

bottom surface of said at least one porous silicon region, said interference monitor comprising a

deep well linear photodiode array of pixels, each pixel having a photoelectron full well capacity

of about 156 million photoelectrons or more, and having a frame rate of about one hundred or

more frames of interference fringe data per second;

e) a fluid flow control system for producing controlled flow of buffer solutions, ligand

containing solutions, and analyte containing solutions through said at least one fluid flow

channel; and

f) a computer processor programmed with a computer program for making causing said

processor to execute kinetic binding measurements based on changes in the spectral interference

patterns monitored by the at least one interference monitor while analytes bind with and

disassociate from ligands attached to surfaces of said pores, said computer program comprising

:a special correlation method executable instructions for calculating optical path differences in

measured interference fringe patterns monitored by said at least one spectral monitor while

analytes bind with and disassociate from ligands attached to surfaces of said pores that are

correlated the measured interference fringe patterns to a test fringe pattern, wherein the test

fringe pattern varies sinusoidally as a function of optical path differences divided by the

wavelength of said light;

wherein said method comprises:

A) immobilizing ligand molecules within said pores;

B) causing a solution containing analyte molecules to flow across said porous silicon region to

permit analyte molecules to diffuse close to and become bound at least temporarily by \underline{to} said

ligand molecules to form interference fringe patterns;

C) illuminating at least a portion of said porous silicon region so as to produce reflections from

said bottom surface and said top surface; and

D) monitoring changes in spectral interference fringe patterns produced by light reflected from

said top and bottom surfaces in order to obtain information concerning binding reactions

between said ligand and said analyte.

38. An optical sensor for monitoring molecular binding interactions, said sensor comprising:

A) at least one porous silicon region comprising more than 1000 pores, each pore having a nominal width and a nominal depth at least 10 times larger than said nominal width, with the depth of each pore being approximately equal to the depth of at least most other pores in said porous silicon region, said porous silicon region defining a top surface and a bottom surface, and said bottom surface being parallel or approximately parallel to said top surface;

- B) at least one buffer-sample fluid flow channel located above said at least one porous silicon region providing a fluid flow passage across said porous silicon region;
- C) at least one light source for illuminating said at least one porous silicon region;
- D) at least one interference monitor adapted to monitor interference patterns caused by interference of light reflected from said top surface with light reflected from said bottom surface of said at least one porous silicon region, said interference monitor comprising a deep well linear photodiode array of pixels, each pixel having a photoelectron full well capacity of about 156 million photoelectrons or more, and having a frame rate of about one hundred or more frames of interference fringe data per second;
- E) a fluid flow control system for producing controlled flow of buffer solutions, ligand containing solutions, and analyte containing solutions through said at least one fluid flow channel; and
- F) a processor means programmed with a computer program for making causing said processor means to execute kinetic molecular binding measurements based on changes in the interference patterns monitored by the at least one interference monitor while analytes bind with and disassociate from ligands attached to surfaces of said pores, said computer program comprising in special correlation method executable instructions for calculating optical path differences in

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measured interference fringe patterns ealeulation of optical path differences from measured interference fringe patterns wherein each measured fringe pattern is that are correlated to a test fringe pattern, wherein the test fringe pattern varies sinusoidally as a function of optical path differences divided by the wavelength of said light.

- 41. An optical sensor for monitoring molecular binding interactions, said sensor comprising:
- A) at least one porous silicon region, said porous silicon region defining a top surface and a bottom surface, <u>and</u> said bottom surface being parallel or approximately parallel to said top surface:
- B) at least one buffer-sample fluid flow channel located above said at least one porous silicon region providing a fluid flow passage across said porous silicon region:
- C) at least one light source for illuminating said at least one porous silicon region;
- D) at least one interference monitor adapted to monitor interference patterns caused by interference of light reflected from said top surface with light reflected from said bottom surface of said at least one porous silicon region, said interference monitor comprising a deep well linear photodiode array of pixels, each pixel having a photoelectron full well capacity of about 156 million photoelectrons or more, and having a frame rate of about one hundred or more frames of interference fringe data per second;
- E) a fluid flow control system for producing controlled flow of buffer solutions, ligand containing solutions, and analyte containing solutions through said at least one fluid flow channel; and

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F) a computer processor programmed with a computer program for making causing said processor to execute molecular binding measurements based on changes in the interference patterns monitored by the at least one interference monitor while analytes bind with and disassociate from ligands attached to surfaces of said pores, said computer program comprising a special correlation method executable instructions for calculating optical path differences in measured interference fringe patterns calculation of optical path differences from measured interference fringe patterns wherein each measured fringe pattern is that are correlated to a test fringe pattern, wherein the test fringe pattern varies sinusoidally as a function of optical path differences divided by the wavelength of said light.

- 42. An optical sensor for monitoring molecular binding interactions, said sensor comprising:
- A) at least one porous silicon region comprising more than 1,000 pores, each pore having a nominal width and a nominal depth at least 10 times larger than said nominal width, with the depth of each pore being approximately equal to the depth of at least most other pores in said porous silicon region, said porous silicon region defining a top surface and a bottom surface, and said bottom surface being parallel or approximately parallel to said top surface;
- B) at least one buffer-sample fluid flow channel located above said at least one porous silicon region providing a fluid flow passage across said porous silicon region;
- C) at least one light source for illuminating said at least one porous silicon region;
- D) at least one interference monitor adapted to monitor interference patterns caused by interference of light reflected from said top surface with light reflected from said bottom surface of said at least one porous silicon region, said interference monitor comprising a deep well linear

photodiode array of pixels, each pixel having a photoelectron full well capacity of about 156 million photoelectrons or more, and having a frame rate of about one hundred or more frames of interference fringe data per second;

- E) a fluid flow control system for producing controlled flow of buffer solutions, ligand containing solutions, and analyte containing solutions through said at least one fluid flow channel; and
- F) a computer processor programmed with a computer program for making causing said processor to execute molecular concentration measurements based on changes in the interference patterns monitored by the at least one interference monitor while analytes bind with and disassociate from ligands attached to surfaces of said pores, said computer program comprising a special correlation method executable instructions for calculating optical path differences in measured interference fringe patterns ealeulation of optical path differences from measured interference fringe patterns wherein each measured fringe pattern is that are correlated to a test fringe pattern, wherein the test fringe pattern varies sinusoidally as a function of optical path differences divided by the wavelength of said light.
- 45. The optical sensor as in claim 1, wherein said <u>sensor</u> is adapted to produce fringe patterns with signal to noise ratios of about 90,000.

The following is an examiner's statement of reasons for allowance: the prior art fails to teach a test fringe pattern that varies sinusoidally as a function of optical path differences divided by the wavelength of the light.

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Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably accompany the issue fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance"

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Nelson Yang whose telephone number is (571)272-0826. The examiner can normally be reached on 8:30-5:00.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Long V. Le can be reached on (571)272-0823. The fax phone number for the organization where this application or proceeding is assigned is 571-273-8300.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free). If you would like assistance from a USPTO Customer Service Representative or access to the automated information system, call 800-786-9199 (IN USA OR CANADA) or 571-272-1000.

/Nelson Yang/ Patent Examiner, Art Unit 1641 Application Number

 Application/Control No.
 Applicant(s)/Patent under Reexamination

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 Examiner
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 Nelson Yang
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